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Notice of Allowability	Application No.	Applicant(s)
	09/700,577	ASCHNER ET AL.
	Examiner	Art Unit
	Gregory A. Wilson	3749
The MAILING DATE of this communication apperall claims being allowable, PROSECUTION ON THE MERITS IS nerewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIP of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in this app or other appropriate communication IGHTS. This application is subject to	plication. If not included will be mailed in due course. <b>THIS</b>
2. ☑ The allowed claim(s) is/are <u>15-26</u> .		
B. $\boxtimes$ The drawings filed on <u>13 November 2000</u> are accepted by	the Examiner.	
<ul> <li>Acknowledgment is made of a claim for foreign priority under the complex of the complex of the complex of the priority documents have a complex of the priority documents have complex of the certified copies of the priority documents have complex of the certified copies of the priority documents have complex of the certified copies of the priority documents have complex of the priority documents have complex of the certified copies of the priority documents have complex of the priority documents.</li> </ul>	e been received. e been received in Application No	
Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONN THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.	of this communication to file a reply MENT of this application.	complying with the requirements
<ol> <li>A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give</li> </ol>	nitted. Note the attached EXAMINER es reason(s) why the oath or declara	'S AMENDMENT or NOTICE OF ation is deficient.
<ol> <li>CORRECTED DRAWINGS (as "replacement sheets") must</li> <li>(a) ☐ including changes required by the Notice of Draftspers</li> <li>1) ☐ hereto or 2) ☐ to Paper No./Mail Date</li> <li>(b) ☐ including changes required by the attached Examiner'</li> <li>Paper No./Mail Date</li> </ol>	son's Patent Drawing Review (PTO s Amendment / Comment or in the C	Office action of
Identifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in t	l.84(c)) should be written on the drawii the header according to 37 CFR 1.121(	ngs in the front (not the back) of d).
<ol> <li>DEPOSIT OF and/or INFORMATION about the depo attached Examiner's comment regarding REQUIREMENT</li> </ol>	sit of BIOLOGICAL MATERIAL I FOR THE DEPOSIT OF BIOLOGIC	must be submitted. Note the PAL MATERIAL.
Attachment(s) 1. ⊠ Notice of References Cited (PTO-892)	5. ☐ Notice of Informal F	Patent Application (PTO-152)
2. ☐ Notice of Praftperson's Patent Drawing Review (PTO-948)	6. ☐ Interview Summary	(PTO-413),
3. ☑ Information Disclosure Statements (PTO-1449 or PTO/SB/0	Paper No./Mail Da 08), 7. ⊠ Examiner's Amendi	
Paper No./Mail Date  4. Examiner's Comment Regarding Requirement for Deposit		ent of Reasons for Allowance
of Biological Material	9.  Other	
GREGORY WILSON  J. PRIMARY EXAMINER  J. J		

U.S. Patent and Trademark Office PTOL-37 (Rev. 1-04) Application/Control Number: 09/700,577

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## **EXAMINER'S AMENDMENT**

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview, with Robert Becker on February 9, 2004.

The application has been amended as follows:

On page 8, line 22, changed "control lever 22" to -control lever 27--,

Cancelled claim 14,

Claim 15 (Amended) An apparatus for the thermal treatment of substrates, comprising:

a housing having a reaction chamber; and

a temperature-compensating element disposed in said reaction chamber for surrounding an outer periphery of a substrate, wherein said compensating element is spaced from said substrate and is essentially disposed in the plane of said substrate, wherein said compensating element is at least partially pivotable in said reaction chamber relative to said plane of said substrate[.],

wherein a pivot device is disposed in said reaction chamber.

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The following is an examiner's statement of reasons for allowance: The primary reason for allowance is that prior art does not teach a method and apparatus for the thermal treatment of substrates in which a temperature compensating element surrounds the outer periphery of a substrate and is pivoted by a pivot device to allow for free access to the substrate within a heating chamber.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Gregory A. Wilson whose telephone number is (703) 308-1239. The examiner can normally be reached on 7 am - 4:30 pm EST.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Ira Lazarus can be reached on (703)308-1935. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

GREGORY WILSON

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February 9, 2004